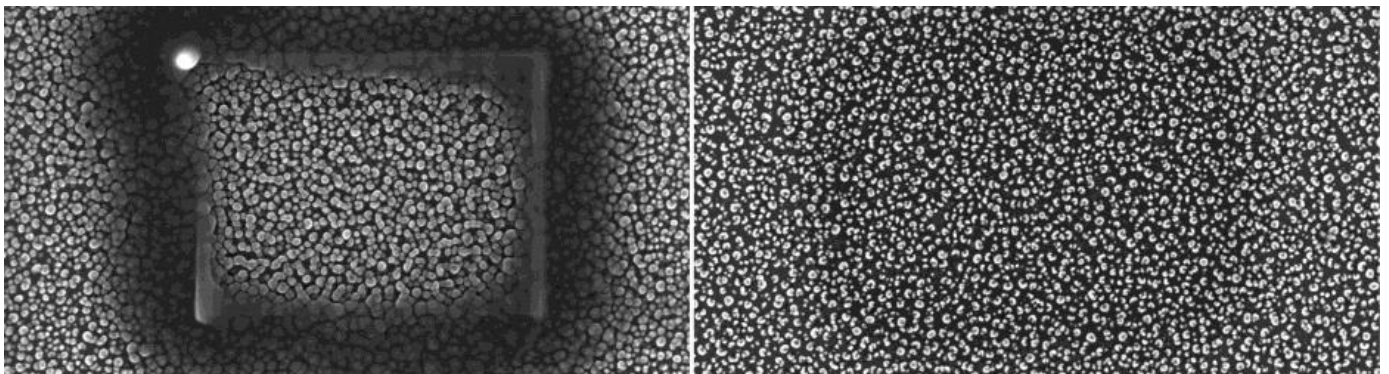


# Effective sample decontamination and high quality images

## ZEISS Plasma Cleaner

There is an increasing need for decontamination systems in Field Emission Scanning Electron Microscopes and Crossbeam instruments. At low (< 5 kV) and extremely low (< 1 kV) SEM acceleration voltages, contamination of the sample with hydrocarbons is likely to happen, and this may prevent the user from achieving the best possible imaging results.

Get a fast and cost-efficient solution for specimen and chamber decontamination: A Plasma Cleaner generates reactive gas-phase radicals in a plasma. The radicals migrate into the instrument chamber and chemically react with the unwanted hydrocarbons.



Sample image taken without Plasma Cleaner.

Sample image taken with Plasma Cleaner.

### Highlights

#### Fast specimen decontamination

Purify typical samples in just 2-10 minutes. Full in-depth decontamination of stage and chamber is available too and takes from 5-60 minutes

#### Improved image quality

Decontamination increases the achievable image resolution for high-quality images

#### Secure handling

Handling is completely safe for the equipment (including EDX and EBSD detectors)

### Upgrade Your ZEISS Microscope

Upgrade your ZEISS microscope with the Plasma Cleaner upgrade and benefit from quick sample decontamination and higher quality of your images.

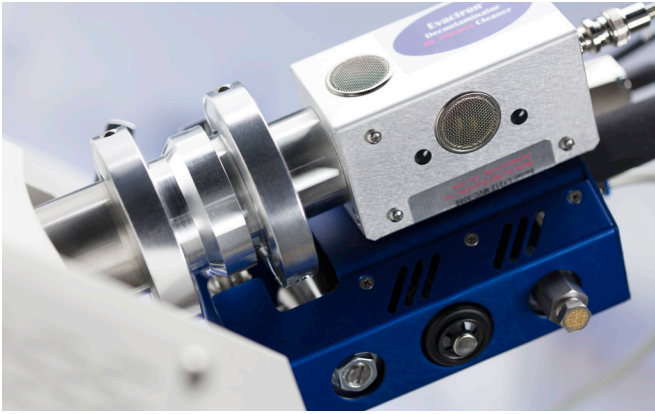
As technical requirements may apply on some systems, please contact us to learn more about the Plasma Cleaner and how your processes will benefit from an upgrade: [microscopy@zeiss.com](mailto:microscopy@zeiss.com)



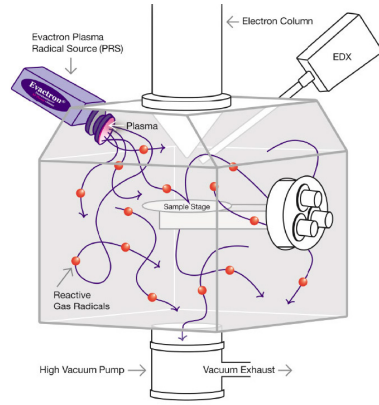
Seeing beyond

# ZEISS Plasma Cleaner

## High quality images



Plasma Cleaner on ZEISS microscope.



Operation principles of the Plasma Cleaner option.

### Availability

- Crossbeam series
- GeminiSEM series
- MERLIN series
- Sigma series
- EVO series
- AURIGA series
- ULTRA series
- SUPRA series
- NVision series
- NEON series
- 15xx XB series
- 15xx series

